



FORM PTO-1449 (REV. 6-89) INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)	U.S. DEPARTMENT OF COMMERCE Patent and Trademark Office	Attorney's Docket No. 4616 US	Serial No. 09/724,633
		Applicant Bakker, et al.	
		Filing Date November 28, 2000	Group Art Unit To Be Assigned

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
Aux	A	5 2 2 6 1 1 8	07/6/93	Baker et al.	395	161	01/29/91

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
Aux	B	WO99/59200	18/11/99	PCT				
Aux	C	WO99/67626	29/12/99	PCT				
Aux	D	WO00/03234	20/01/00	PCT				

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

Aux	E	Extended Kohonen Maps web pages [online] [retrieved on 1999-10-28]. Retrieved from the Internet: <URL: http://www.grid.let.rug.nl/~kleiweg/kohonen > 6 Pages
	F	Karnowski, Thomas P., Tobin, Kenneth W., Gleason, Shaun S., Fred Lakhani "The Application of Spatial Signature Analysis to Electrical Test Data Validation Study" Oak Ridge National Laboratory, Oak Ridge, TN 37831-6011, Sematech, Austin, TX 78741-6499, 12 Pages
Aux	G	Electroglas.com web pages, "Spatial Pattern Recognition" [online] [retrieved on 2000-11-28]. Retrieved from the Internet: <URL: http://www.electroglas.com/products/knights_datasheets/spar_ds.htm > 4 Pages
	H	Dym.com web pages, "Spatial Signature Analysis (SSA)" [online] [retrieved on 2000-11-28]. Retrieved from the Internet: <URL: http://www.dym.com/ssa.htm > 2 Pages
Aux	I	Oak Ridge National Laboratory web pages, "ORNL-SEMATAch Computing Tools Helps U.S. Semiconductor Industry Identify Manufacturing Problems" [online] [retrieved on 2000-11-28]. Retrieved from the Internet: <URL: http://www.ornl.gov/Press_Releases/archive/mrl19980804-00.html > 2 Pages
	J	ISMV Semiconductor web pages, "Semiconductor Spatial Signature Analysis (SSA)", [online] [retrieved on 2000-11-28]. Retrieved from the Internet: <URL: http://www.ismv.ic.ornl.gov/projects/SSA.html > 6 Pages.

EXAMINER 	DATE CONSIDERED 3/15/04
--------------	----------------------------

EXAMINER: Initial if references considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered.
Include copy of this form with next communication to applicant.

[illegible]